

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/388,826
Filing Date September 1, 1999
Inventor Weimin Li et al.
Assignee Micron Technology, Inc.
Group Art Unit 2822
Examiner T. Thomas
Attorney Docket No. MI22-1208
Title: Low K Interlevel Dielectric Layer Fabrication Methods



10/Suppl.
I.D.S.
G. Stanley
5-31-01

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the documents listed on the accompanying PTO-1449 are enclosed. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 5-22-01

By: 
Mark S. Matkin
Reg. No. 32,268